

**FORM PTO-1449**

## INFORMATION DISCLOSURE CITATION IN AN APPLICATION

*(Use several sheets if necessary)*

**Docket Number (Optional)**  
15.44/5852

**Application Number**  
not assigned

**Applicant**  
**KUWAZAWA**

**Filing Date**  
**June 19, 2001**

**Group Art Unit**  
**not assigned**

**U.S. PATENT DOCUMENTS**

[illegible]

## FOREIGN PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS													
	DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	Translation	
												YES	NO

**OTHER DOCUMENTS** *(Including Author, Title, Date, Pertinent Pages, Etc.)*

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
5 DI	Morifuji, et al. "An 80 nm Dual-gate CMOS with Shallow Extensions Formed after Activation Annealing and SALICIDE," March 1999, IEEE 0-7803-5413, 4 pp.

EXAMINER <i>Stanette Chan</i>	DATE CONSIDERED <i>5/10/02</i>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.